



IPW

PATENT  
Customer No. 22,852  
Attorney Docket No. 04329.3300

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
)  
Takashi Sato et al. ) Group Art Unit: 1756  
)  
Application No.: 10/814,303 ) Examiner: ROSASCO, Stephen D.  
)  
Filed: April 1, 2004 )  
)  
For: EXPOSURE METHOD, ) Confirmation No.: 8598  
EXPOSURE QUANTITY )  
CALCULATING SYSTEM USING )  
THE EXPOSURE METHOD AND )  
SEMICONDUCTOR DEVICE )  
MANUFACTURING METHOD )  
USING THE EXPOSURE )  
METHOD )

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT**

In reply to the Office Action mailed January 4, 2006, the period for response extending through April 4, 2006, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks** follow the amendment sections of this paper.